

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihide TSUBATA et al. Application No.: 10/595,640 Filing or 371(c) Date: May 2, 2006 Title: TRANSISTOR AND CVD APPARATUS USED TO DEPOSIT GATE INSULATING FILM THEREOF	Art Unit: 2818 Examiner: E. TAYLOR
--	---

INFORMATION DISCLOSURE STATEMENT COVER LETTER

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 CFR § 1.56, Applicant submits references, including references cited in any included Official Communication issued in a corresponding non-U.S. application, with the attached Form PTO/SB/08a.

Where available, Applicant has provided:

1) English language equivalents of the foreign language references cited in the included Official Communication or Applicant's Specification and has not provided the foreign language references;

2) English language abstracts of the provided foreign language references obtained from a corresponding foreign Patent Office; and

3) English machine translations of the provided Japanese references that were prepared by the Intellectual Property Digital Library of the Japanese Patent Office.

The statement is not a representation that all of the information cited is necessarily effective as prior art against the application.

Respectfully submitted,

Dated: January 23, 2008

/Christopher A. Bennett #46,710/
Attorneys for Applicant

KEATING & BENNETT, LLP
8180 Greensboro Drive, Suite 850
Tyson's Corner, VA 22102
Telephone: (703) 637-1480
Facsimile: (703) 637-1499

Joseph R. Keating
Registration No. 37,368

Christopher A. Bennett
Registration No. 46,710